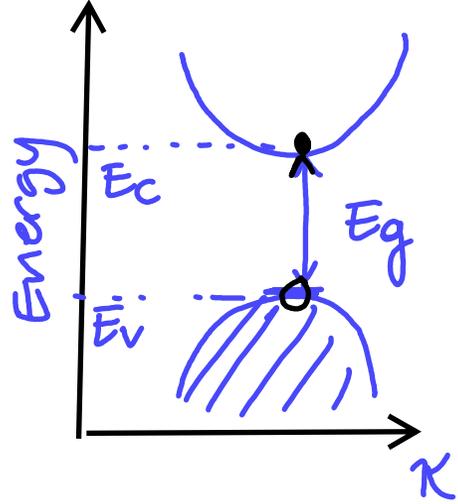


Semiconductors

Lecture 2

SEMICONDUCTORS

Recap

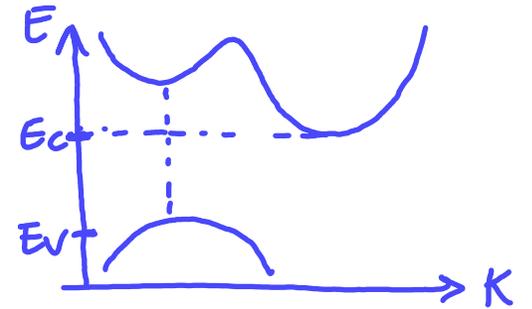


Conduction Band

Valence Band

↓ DIRECT BAND GAP

* INDIRECT BAND GAP



Hole

$$\bar{k}_h = -\bar{k}_e$$

$$E_h(\bar{k}_h) = -E_e(k_e)$$

$$\sigma_h = \sigma_e$$

$$m_h^* = -m_e^*$$

$$q_{\text{hole}} = +e$$

Recap

- * concentration of e^- in the C.B. $n(T) \propto e^{-\frac{E_c - \mu}{k_B T}}$
- * concentration of h^+ in the V.B. $p(T) \propto e^{-\frac{\mu - E_v}{k_B T}}$

* Law of mass action $n \cdot p = 4 \left(\frac{k_B T}{2\pi \hbar^2} \right) (m_e^* m_h^*)^{3/2} e^{-E_g / k_B T}$

$$E_g = E_c - E_v$$

* Intrinsic semiconductor $n_i = p_i$

$$\mu(T) = \frac{E_v + E_c}{2} + \frac{3}{4} k_B T \ln \frac{m_h^*}{m_e^*}$$



Intrinsic mobility

Mobility. $\mu_i = \frac{|\sigma|}{E}$

$$\left[\frac{\text{m}^2}{\text{Vs}} \right]$$

do not confuse it with the chemical potential!

μ_i is defined positive for both e- and h!

- electric conductivity ($\sigma = 1/\rho$)

$$\sigma_e = \frac{j_e}{E} = \frac{n(T)e\sigma_e}{E} = n(T)e\mu_e$$

$$\sigma_h = \dots = p(T)e\mu_h$$

$$\sigma_{\text{TOTAL}} = \sigma_e + \sigma_h = n(T)e\mu_e + p(T)e\mu_h$$

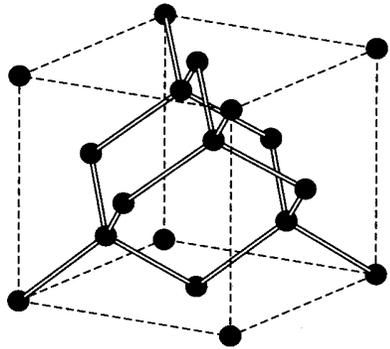
- drift velocity $v = q\tau \frac{E}{m} \Rightarrow \mu_e = \frac{e\tau_e}{m_e}$ & $\mu_h = \frac{e\tau_h}{m_h}$

τ : collision time

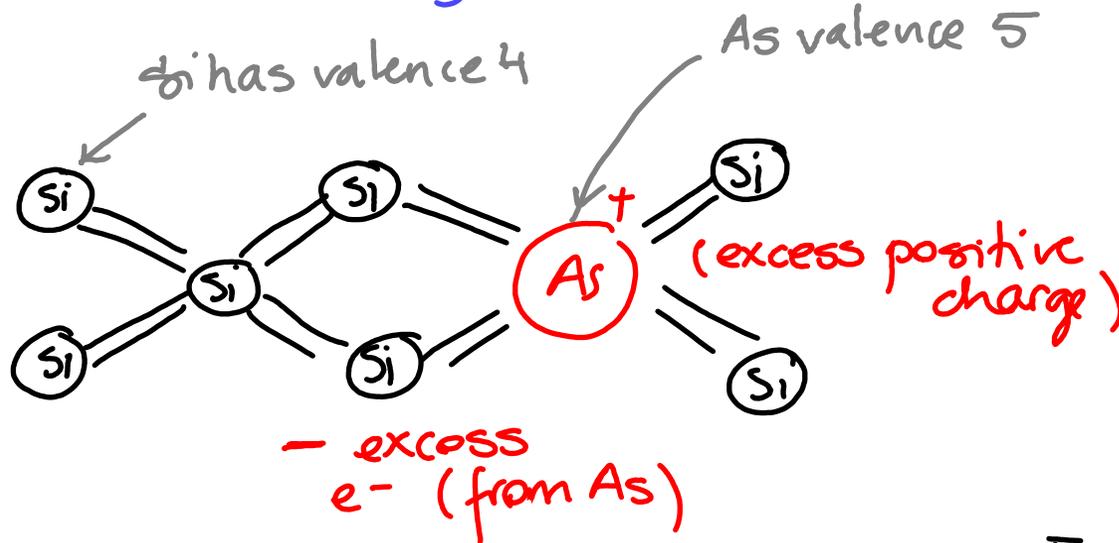
Doping of semiconductors

Ex 0.001% of B in Si \rightarrow conductivity $\times 1000$!

| | | |
|---|---|--|
| 13 IIIA 5 B Boron 10.81 2.2 | 14 IVA 6 C Carbon 12.01 2.4 | 15 VA 7 N Nitrogen 14.01 3.5 |
| 13 Al Aluminum 26.98 2.8 | 14 Si Silicon 28.09 2.4 | 15 P Phosphorus 30.97 3.5 |
| 31 Ga Gallium 69.72 2.4-3.0 | 32 Ge Germanium 72.63 2.4-3.4 | 33 As Arsenic 74.92 3.5 |
| 49 In Indium 114.82 2.8-3.0 | 50 Sn Tin 118.71 2.0-3.4 | 51 Sb Antimony 121.76 3.5 |



Diamond structure
(Si, Ge)



\Rightarrow semiconductor type-n
As = Donor (e^-)

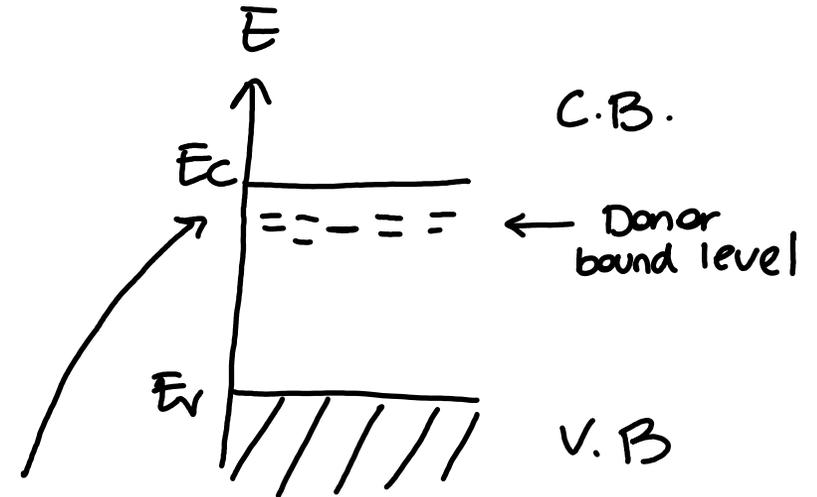
Where is the energetic level of the impurity?

Hydrogen atom $E_{ion} = -\frac{e^4 m}{2(4\pi\epsilon_0\hbar)^2} = 13.6 \text{ eV}$

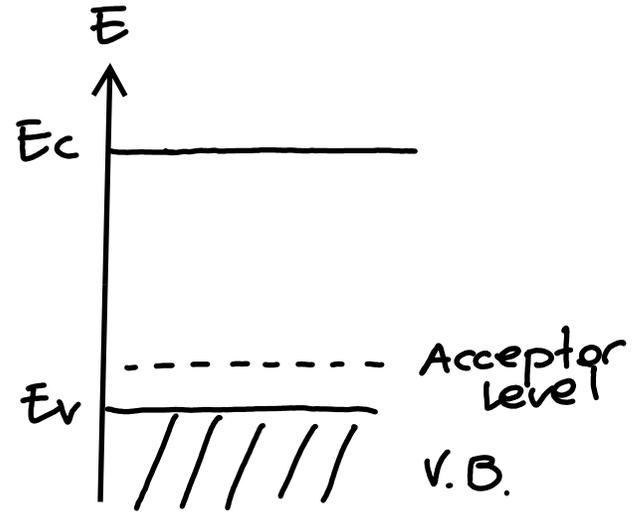
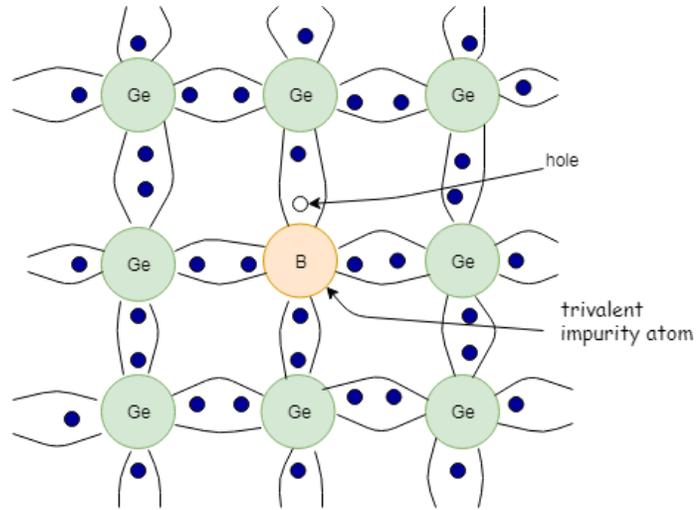
$E_c - E_{donor} = \frac{e^4 m_e^*}{2(4\pi\epsilon_0\hbar)^2} \sim 10 \text{ meV}$

$E \sim 10$
 $m_e^* \sim 0.1 m_e$

Donor impurity forms an energy eigenstate just below the bottom of C.B.



Acceptors



Doping type - p : the doped semiconductor has excess of holes

Nomenclature

Type n: carriers are free e^- in the conduction band given at RT by ionized donors

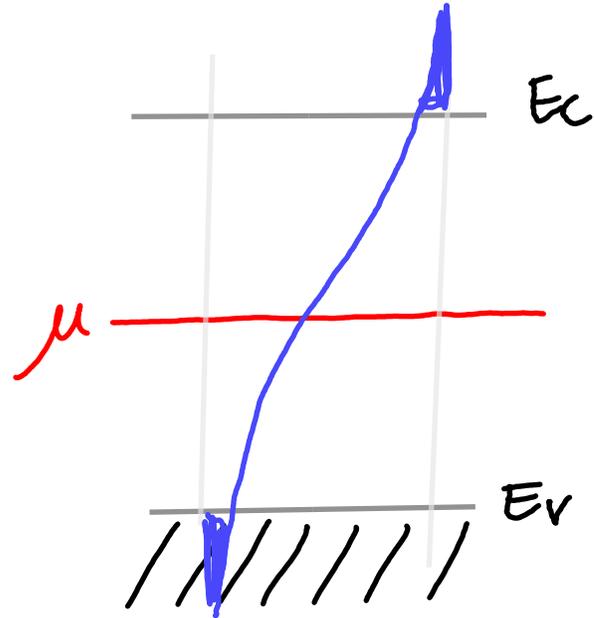
Type p: carriers are free holes in the valence band given at RT by ionized acceptors

Intrinsic: pure semiconductor, $n = p$ without doping

For all n and p , np only depends on:

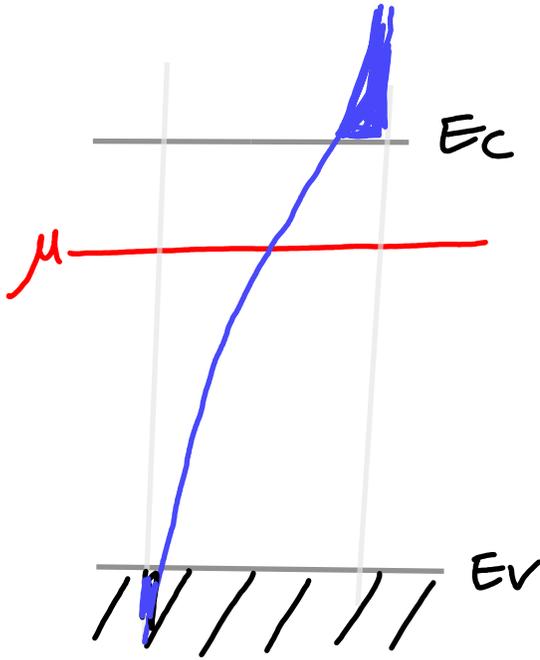
- intrinsic material
- temperature

Ferui level changes if one modifies the balance n, p



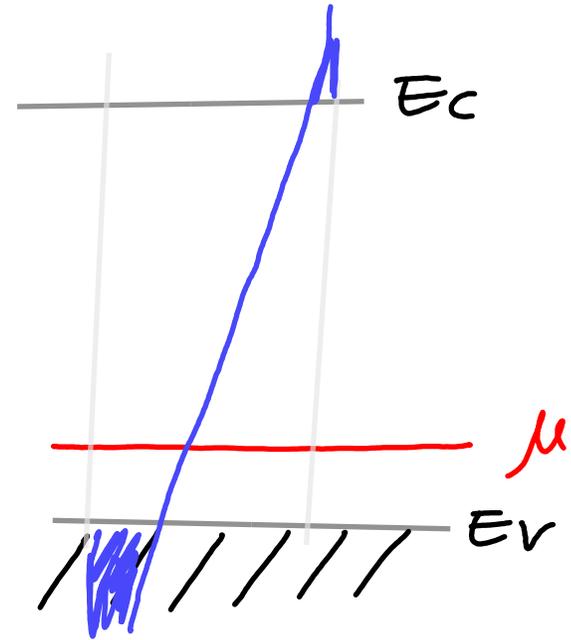
$$n=p$$

absence of impurities,
the Ferui. level (chemical
potential at 0K) is in the
middle of the gap



$$n > p$$

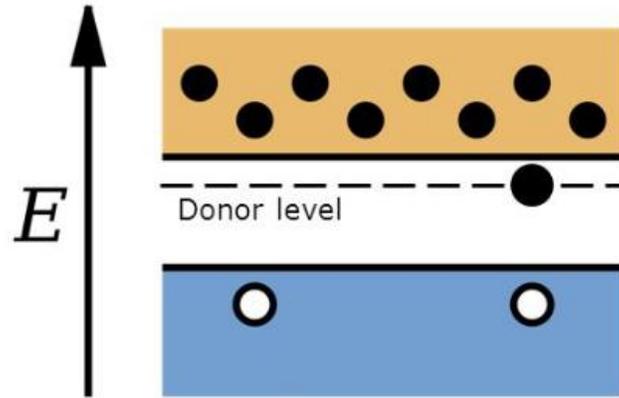
Donnors



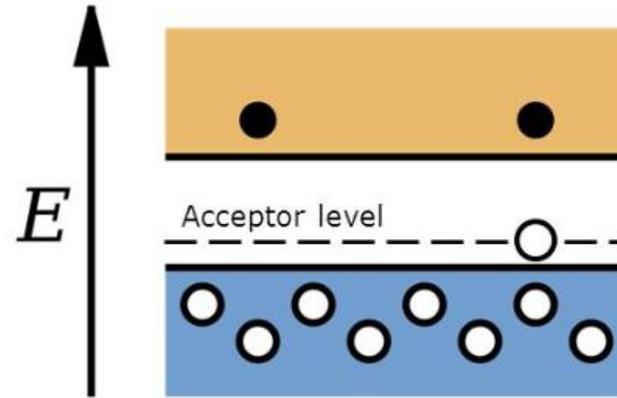
$$n < p$$

Acceptors

n-type band structures :



p-type band structures :



Group IV semiconductors:

Si and Ge
Donors: P and As

Group III-V semiconductors:

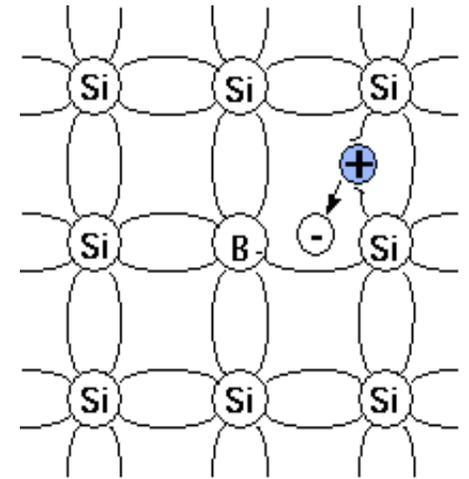
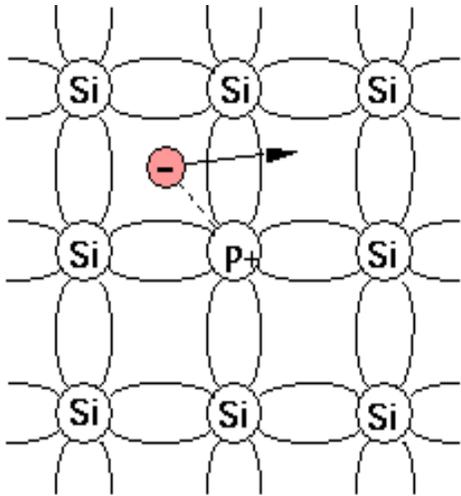
GaAs and GaN
Donors: Se, Te, Si and Ge

Group IV semiconductors:

Si and Ge
Acceptors: B and Al

Group III-V semiconductors:

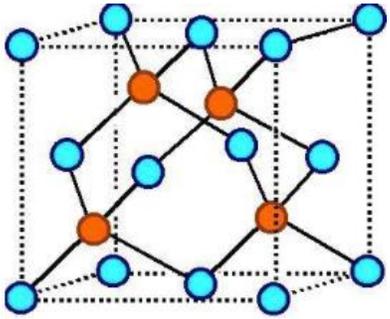
GaAs and GaN
Acceptors: Be, Zn, Cd and Ge



Semiconductor devices

Band structure engineering

Designing band gaps



zinc blende structure

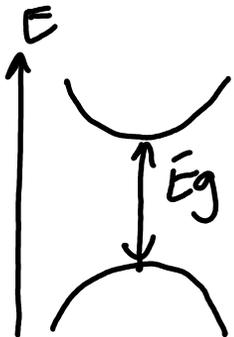
$$\text{GaAs} - E_{\text{gap}} = 1.4 \text{ eV}$$

$$\text{AlAs} - E_{\text{gap}} = 2.7 \text{ eV}$$



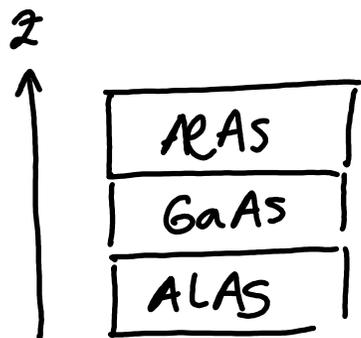
$$E_{\text{gap}}(x) = (1-x) 1.4 \text{ eV} + x 2.7 \text{ eV}$$

As first approx., the direct band gap interpolates those of GaAs and AlAs



Semiconductor lasers
(520nm, 445nm, 635nm)

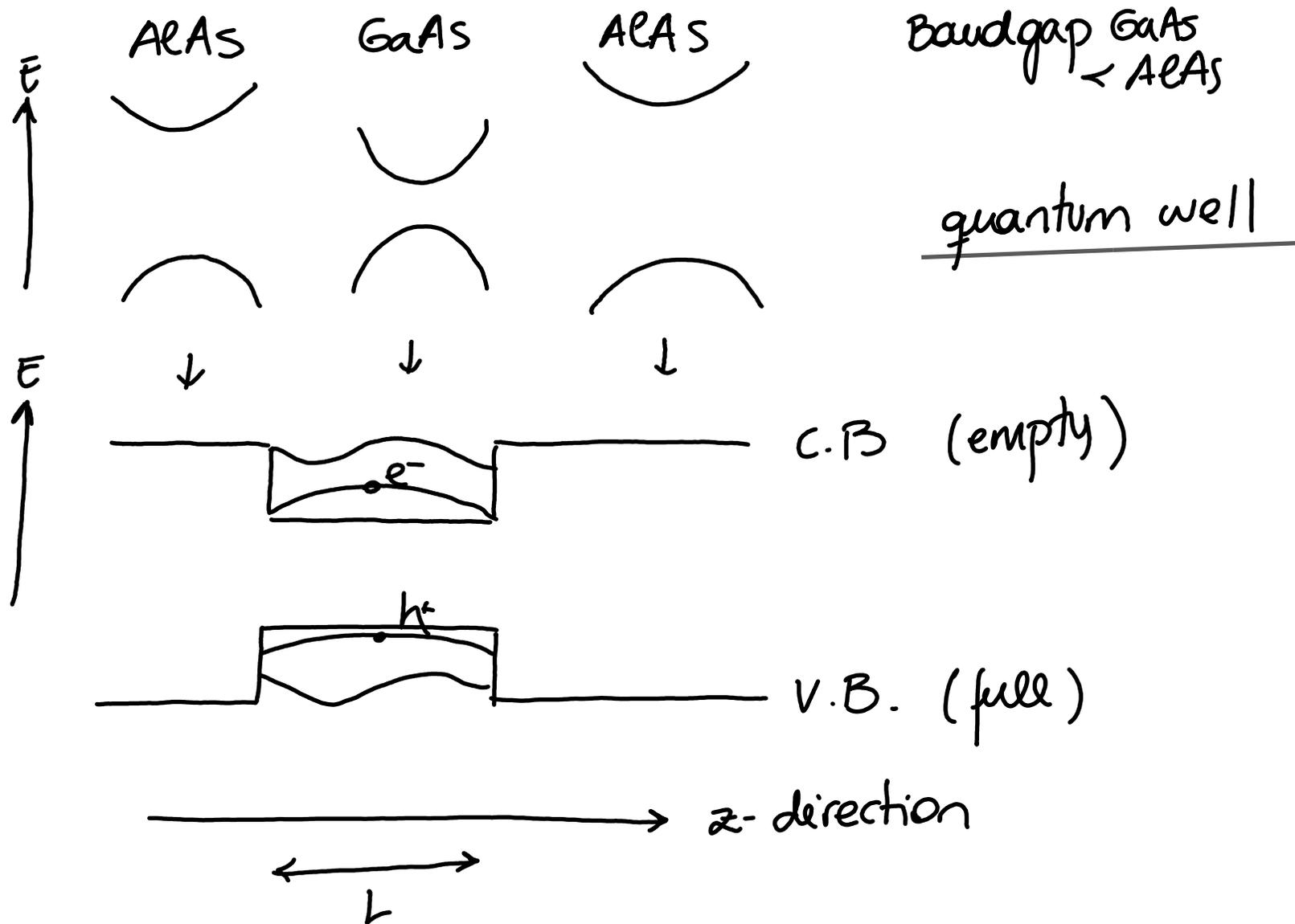
Non-homogeneous band gaps



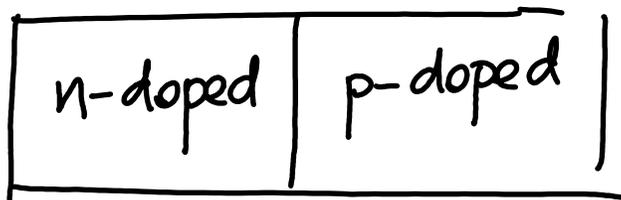
heterostructure

e^- in a semiconductor see the energy in the c.B. bottom as a potential as function of position in which they can be trapped.

(idea for holes and top of the v.B.)

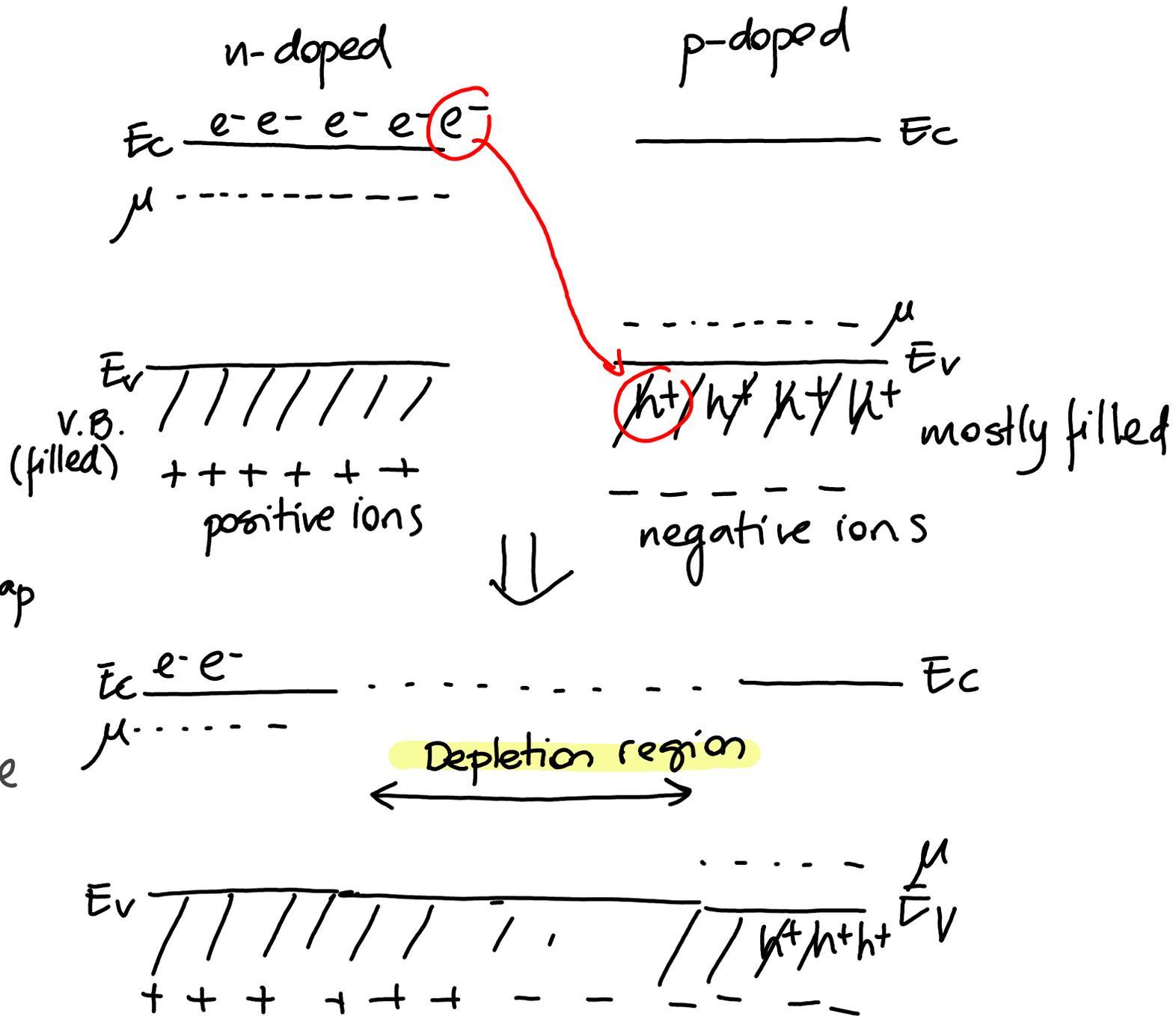


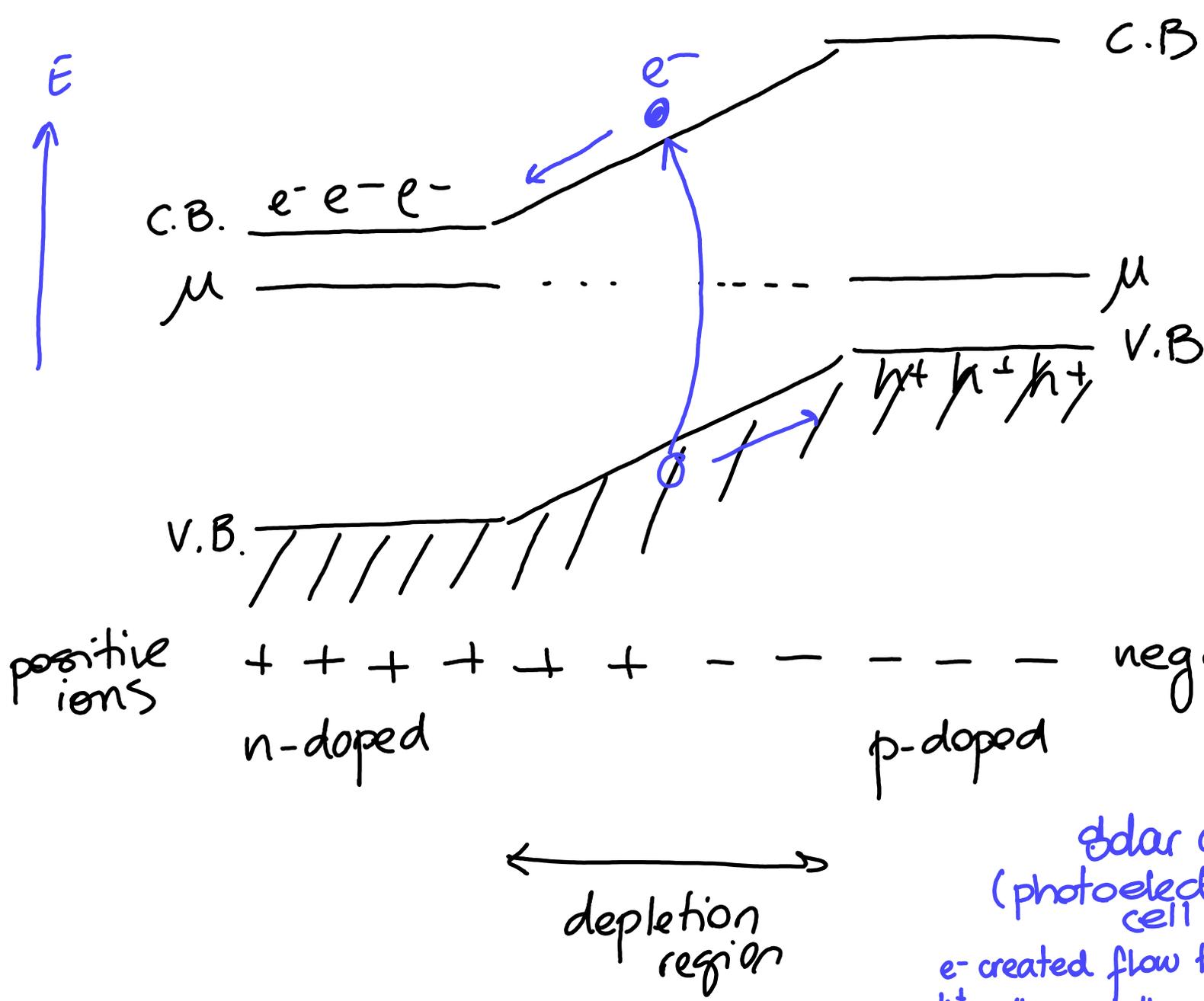
p-n Junction



When the 2 materials are brought together, e^- in c.B. will fall in the v.B. to annihilate holes \rightarrow this annihilating process gains an energy E_{gap}

\Downarrow
As a result, there will be a region close to the interface where there are no more free carriers \Rightarrow "depletion region" or "space charge region"





Due to annihilating processes, there are no more free carriers in the depletion region, but the negative and positive charged ions still remain there

\Downarrow
 \Rightarrow now a net electric field

If one e^- wants to cross this region to annihilate a h^+ , it has an energy cost to overcome $-e\Delta\phi$ electrostatic potential

\Downarrow
 Depletion region width determined by energy compensation
 $E_g = e\Delta\phi$

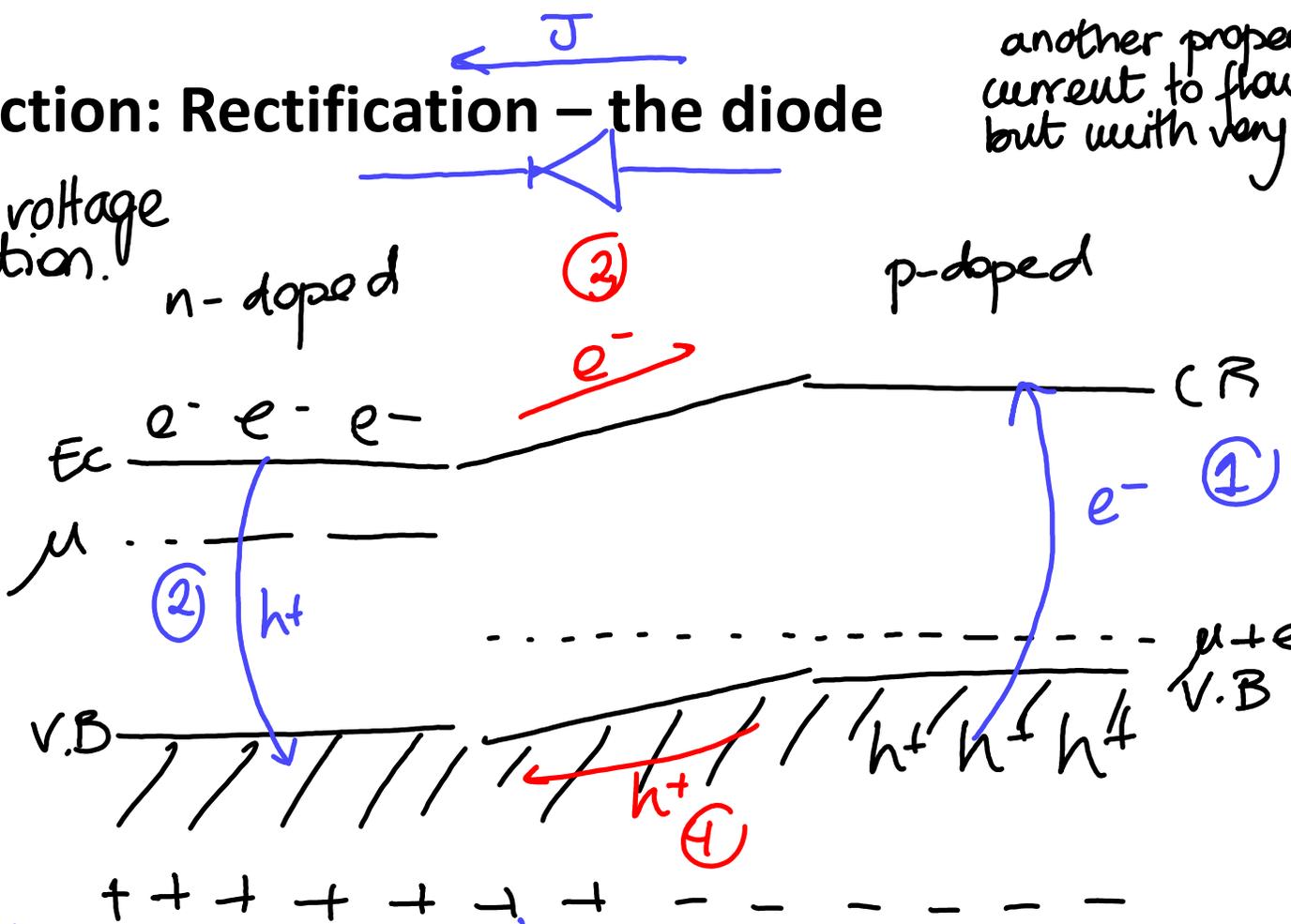
Edar cell: put in phonons \rightarrow get current
 (photoelectric cell)

e^- created flow to the left (n-doped)
 h^+ " " " " right (p-doped) } In both cases, current is moving to the right

p-n Junction: Rectification – the diode

another property of p-n junctions: allows current to flow easily in one direction but with very high R in the other

Let's apply a voltage to a pn junction.



bend downwards due to the applied voltage

Processes that can create current

①, ② # of carriers: typically activated form $\sim e^{-E_g/K_B T}$: $I_{right} \propto e^{-E_{gap}/K_B T}$

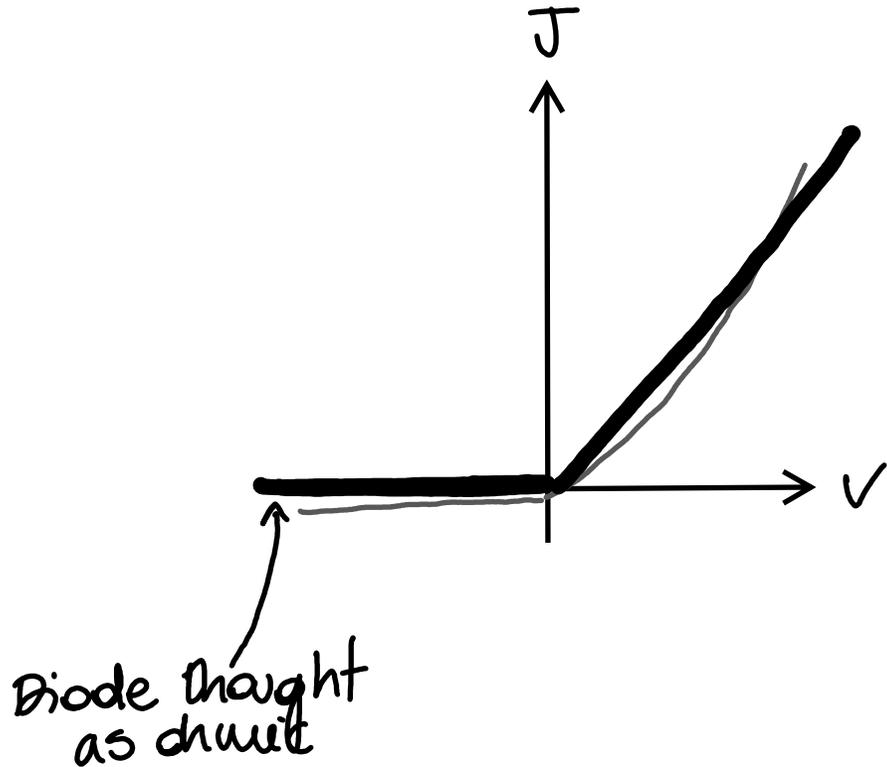
③, ④ e^- in the CB at n-doped side (left diagram) might be thermally activated to climb slope in the depletion region, and then annihilated with h^+ at p-side
 If voltage applied, height potential becomes $E_g + eV \Rightarrow$ current of these processes $I_{left} \propto e^{-\frac{(E_{gap} + eV)}{K_B}}$

idem with holes

Total current $J_{\text{left}} + J_{\text{right}}$, and taking into account that $J(V=0)=0$:

$$J \sim \underbrace{e^{-\frac{E_{\text{gap}}}{k_B T}}}_{J_s = \text{saturation current}} \left(e^{-\frac{eV}{k_B T}} - 1 \right)$$

DIODE EQUATION



Symbol (current flows easy in the arrow direction)

